

Form PTO-1449 (REV. 8-83) SEP 24 2004 U.S. Department of Commerce Patent and Trademark Office		Atty. Docket: 0492611-0510 (MIT 10443),		In re Application No. 10/669,883	
INFORMATION DISCLOSURE STATEMENT <i>(Use several sheets if necessary)</i>		Applicant: Manalis, et al.			
		Filing Date: September 23, 2003		Group:	
U.S. PATENT DOCUMENTS					
Examiner's Initials	U.S. Patent No.	Applicant	Issue Date	Class	Subclass
U.S. PATENT APPLICATIONS					
Examiner's Initials:	Publication Number:	Applicant:	Publication Date:	Group:	Art Unit:
W	2004/0038426	Manalis	February 26, 2004	\	
FOREIGN PATENT DOCUMENTS					
Examiner's Initials	Document No.	Country	Date	Translation	
				Yes	No
OTHER DOCUMENTS					
Examiner's Initials	Citation (Including Author, Title, Date, Pertinent Pages, Etc.)				
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K	2002/0137084	Quate et al.	September 26, 2002		

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









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